

operational amplifier and a negative feedback circuit.

18. The [integrated circuit] interface of claim 17 wherein said negative feedback circuit is an input-sensing, output driving feedback circuit.
19. The [integrated circuit] interface of claim 17 wherein said micromechanical structure includes a first proof mass and a second proof mass.
20. The [integrated circuit] interface of claim 19 wherein said first proof mass comprises [a] said first sense capacitor and said second proof mass comprises [a] said second sense capacitor.
21. The [integrated circuit] interface of claim 20 wherein said first and second sense capacitors are coupled in said feedback circuit.
22. The [micromechanical system] interface of claim 20 wherein said first proof mass and said second proof mass are connected so as to electrically decouple said sense capacitors.
23. The [integrated circuit].interface of claim 17 wherein said micromechanical structure includes:
 - a substrate;
 - at least one proof-mass; and
 - [first and second electrically decoupled sense capacitors; and]wherein said first and second electrically decoupled sense capacitors comprise four independent terminals, each electrically decoupled sense capacitor comprising an independent terminal on said proof mass, and an independent terminal on said substrate.
24. The [micromechanical system] interface of claim 17 wherein said operational amplifier includes at least a first input, and a first signal applied to said feedback circuit places said operational amplifier in unity gain feedback during a first non-overlapping time period.
25. The [micromechanical system] interface of claim 17 wherein a second signal to said feedback circuit